

4. (Currently Amended) Device according to ~~one or more of the preceding claims or in particular according thereto~~ claim 1, characterized in that the substrate holder (2) has one or more substrate-bearing disks (4), which are in particular mounted on a gas bearing and each have an associated insert piece (3).

5. (Currently Amended) Device according to ~~one or more of the preceding claims or in particular according thereto~~ claim 1, characterized in that the insert piece (3) is directly associated with the substrate bearing disk (4) and in particular the entire substrate bearing disk (4) consists of metal.

6. (Currently Amended) Device according to ~~one or more of the preceding claims or in particular according thereto~~ claim 1, characterized by a multiplicity of substrate bearing disks (4) disposed in planetary fashion on a substrate holder.

7. (Currently Amended) Device according to ~~one or more of the preceding claims or in particular according thereto~~ claim 1, characterized in that the substrate bearing disk (4) is located on a gas bearing in a bearing recess (9) in the substrate holder and the insert piece (3) or the more electrically conductive zone is associated with the base of the bearing recess (9).

8. (Currently Amended) Device according to ~~one or more of the preceding claims or in particular according thereto~~ claim 1, characterized in that the one or more insert pieces consist of molybdenum, tantalum, tungsten or the like.

9. (Currently Amended) Device according to ~~one or more of the preceding claims or in particular according thereto~~ claim 1, characterized in that the substrate holder (2) is surrounded by an HF coil (5).

10. (Currently Amended) Device according to ~~one or more of the preceding claims or in particular according thereto~~ claim 1, characterized in that the substrate holder (2) is disposed above an HF coil (5).

11. (Currently Amended) Device according to ~~one or more of the preceding claims or in particular according thereto~~ claim 1, characterized in that the reactor, with which the substrate holder (2) is associated, is a cold-wall reactor, the walls of which are heated only by the radiation of the heated substrate holder (2).

12. (Currently Amended) Device according to ~~one or more of the preceding claims or in particular according thereto~~ claim 1, characterized in that the reactor is a tunnel reactor.

13. (Currently Amended) Device according to ~~one or more of the preceding claims or in particular according thereto~~ claim 1, characterized in that the reactor is a planetary reactor with a central gas feed and a rotating substrate holder (2), which is support for a multiplicity of substrate bearing disks (4) arranged in planetary fashion with respect to the center of the substrate holder (2), which substrate bearing disks (4) in each case rotate on a gas bearing.